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	Applicati n No.	Applicant(s)	V
	09/829,969	OHNISHI`ET AL.	
Notice of Allowability	Examin r	Art Unit	
	Mai-Huong Tran	2818	
Th MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS (herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIG	(OR REMAINS) CLOSED in this ap or other appropriate communicatior GHTS. This application is subject to	plication. If not included n will be mailed in due cours	se. THIS he initiative
 This communication is responsive to 1/20/04. The allowed claim(s) is/are 1-2, 4-6, 8, 1718, 20-23, 25-26. The drawings filed on 11 April 2001 are accepted by the Ex Acknowledgment is made of a claim for foreign priority un a) All b) Some* c) None of the: Certified copies of the priority documents have 	caminer. der 35 U.S.C. § 119(a)-(d) or (f).	·	
2. Certified copies of the priority documents have	been received in Application No	·	
3. Copies of the certified copies of the priority doc	cuments have been received in this	national stage application fr	rom the
International Bureau (PCT Rule 17.2(a)).		0 11	
* Certified copies not received:			
 5. Acknowledgment is made of a claim for domestic priority un reference was included in the first sentence of the specifica (a) The translation of the foreign language provisional at a Acknowledgment is made of a claim for domestic priority un in the first sentence of the specification or in an Application 	tion or in an Application Data Sheet pplication has been received. nder 35 U.S.C. §§ 120 and/or 121 si	. 37 CFR 1.78.	
Applicant has THREE MONTHS FROM THE "MAILING DATE" of below. Failure to timely comply will result in ABANDONMENT of t	his application. THIS THREE-MOI	NTH PERIOD IS NOT EXTE	ENDABLE.
 A SUBSTITUTE OATH OR DECLARATION must be submit INFORMAL PATENT APPLICATION (PTO-152) which give 	s reason(s) why the oath or declara		E OF
 8. ☐ CORRECTED DRAWINGS (as "replacement sheets") must (a) ☐ including changes required by the Notice of Draftsperso 1) ☐ hereto or 2) ☐ to Paper No 		948) attached	
(b) ☐ including changes required by the proposed drawing co	orrection filed, which has be	en approved by the Examir	ner.
(c) ☐ including changes required by the attached Examiner's	Amendment / Comment or in the C	Office action of Paper No	·
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in th) of
9. DEPOSIT OF and/or INFORMATION about the deposattached Examiner's comment regarding REQUIREMENT FOR THE			he
Attachm nt(s)	•		
1⊠ Notice of References Cited (PTO-892)	5☐ Notice of Informal Pa	tent Application (PTO-152)	
 2 Notice of Draftperson's Patent Drawing Review (PTO-948) 3 Information Disclosure Statements (PTO-1449 or PTO/SB/08), Paper No. 	6 Interview Summary (PTO-413), Paper No	
), 7☐ Examiner's Amendm	ent/Comment	
4 Examiner's Comment Regarding Requirement for Deposit of Biological Material	8⊠ Examiner's Statemer 9□ Other .	nt of Reasons for Allowance	!
	The same	•	
Dávid Nelms			
Supervisory Patent Examiner Technology Center 2800			

Application/Control Number: 09/829,969

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DETAILED ACTION

Reason for allowance

The following is an examiner's statement of reason for allowance: None of the references of record teaches or suggests the claimed Semiconductor Device and Process for Producing the Same having the metal silicide layer and the metal nitride layer that are formed as individual layers to function as a contact resistance reducing layer and as a reaction barrier layer, and the metal silicide layer has a thickness of 5 to 20 nm.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Mai-Huong Tran whose telephone number is (571)-272-1796. The examiner can normally be reached on Monday-Thursday 8:00am-6:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571) 272-1787. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 872-9306 for regular communications and (703) 308-7722 for After Final communications.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 872-9319.

Mai-Huong Tran

David Nelms
Supervisory Patent Examiner
Technology Center 2800